

**PATENT NUMBER and
ISSUE DATE**

U.S. UTILITY Patent Application

APPL NUM 10000458	FILING DATE 11/30/2001	CLASS 250	SUBCLASS U 12.22	GAU 2881	EXAMINER EL-SHAMMAA
**APPLICANTS: Yahiro Takehisa;					
**CONTINUING DATA VERIFIED: NONE in E					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2001-033970 02/09/2001 JAPAN 2001-043195 02/20/2001					
PG-PUB		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials:				ATTORNEY DOCKET NO 4641-61273	
TITLE : Methods and devices for evaluating beam blur in a charged-particle-beam microlithography apparatus					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg. Print Fig.
		Application Examiner	
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	
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